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On the use of NEXAFS and PSID SEXAFS in the study of adsorbate–semiconductor coordination

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Abstract. Using Si(111)7 × 7–Cl as a model system, we have investigated the use of polarisation-dependent NEXAFS and ion yield SEXAFS in the determination of adsorbate–semiconductor coordination. Cl K-edge Cl⁺ yield data indicate a Cl–Si bond length of 2.01 ± 0.03 Å, in agreement with Cl KLL Auger yield SEXAFS data. The polarisation-dependent behaviour of the ‘white line’ in Auger yield NEXAFS data is found to be consistent with a recently proposed pseudo-intra-molecular σ^* -resonance model.

There has been debate in the literature recently concerning the validity of using photon-stimulated ion desorption (PSID) surface extended x-ray absorption fine structure (SEXAFS) as a means of determining surface bond geometries [1]. In the present work we explored the use of PSID SEXAFS at an adsorbate (Cl) edge in a simple way, i.e.

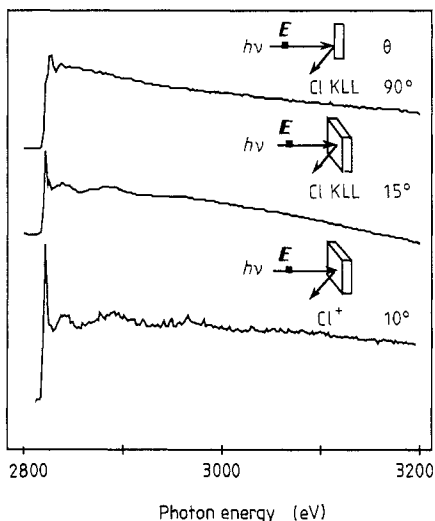


Figure 1. Cl K-edge Auger and ion yield SEXAFS data for Si(111)7 × 7–Cl at angle of incidence θ .

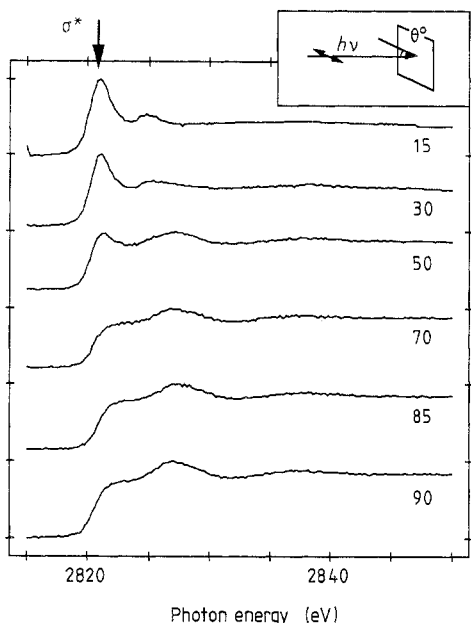


Figure 2. Cl K-edge Cl KLL Auger yield NEXAFS for Si(111)7 \times 7-Cl as a function of photon incidence angle, θ° . The pseudo-intra-molecular σ^* -resonance is indicated.

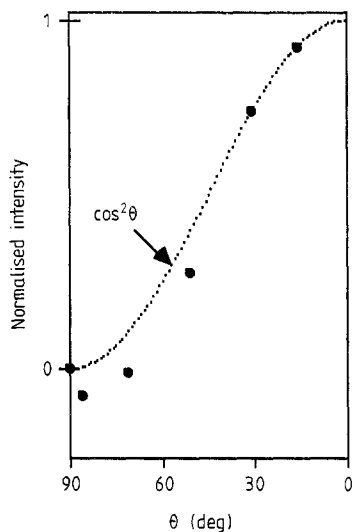


Figure 3. The normalised intensity of the σ^* -resonance obtained from figure 2 (●).

by determining whether the ion yield data indicate the same geometry as the more conventional Auger yield method. The results, which were obtained from a conventionally prepared Si(111)7 \times 7-Cl surface (which has Cl bonded atop Si [2]) using station 6.3 at the SRS, Daresbury Laboratory, are shown in figure 1. Analysis yields the same Cl-Si bond distance and coordination number from ion and Auger yield, showing that for this system at least the ion yield represents a valid SEXAFS measurement technique.

As for the near-edge x-ray absorption fine structure (NEXAFS), we recently suggested the possibility of using adsorbate-semiconductor σ^* -resonances to evaluate the adsorbate bond angle [3]. The validity of this seems to be confirmed by our more recent work, where the intensity of the σ^* -resonance has been recorded as a function of photon incidence (E -vector) angle with respect to the Si-Cl bond (figure 2). After accounting for an atomic-like background, the intensity has the expected [4] $\cos^2 \theta$ dependence (figure 3).

References

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